1. Record Nr. UNISA990000482390203316

Autore	CELANO, Bruno
Titolo	Dialettica della giustificazione pratica : saggio sulla legge di Hume / Bruno Celano
Pubbl/distr/stampa	Torino : Giappichelli, 1994
ISBN	88-348-4055-0
Descrizione fisica	765 p. ; 23 cm
Collana	Analisi e diritto , Serie teorica ; 16
Disciplina	340.1
Soggetti	Filosofia del diritto
Collocazione	XXII.1. Coll. 2/ 3 (COLL POE 16)
Lingua di pubblicazione	Italiano
Formato	Materiale a stampa
Livello bibliografico	Monografia
Note generali	In testa al front.: Università degli studi di Palermo Dipartimento di studi su politica, diritto e società

2. Record Nr. UNINA9910465049103321

Autore	Jones T. B (Thomas Byron), <1944->
Titolo	Electromechanics and MEMS / / Thomas B. Jones, University of Rochester, New York, Nenad G. Nenadic, Rochester Institute of Technology [[electronic resource]]
Pubbl/distr/stampa	Cambridge : , : Cambridge University Press, , 2013
ISBN	1-107-23329-1 1-139-62462-8 1-107-25359-4 1-139-03260-7 1-139-61532-7 1-139-61160-7 1-139-62090-8
Descrizione fisica	1 online resource (xx, 559 pages) : digital, PDF file(s)
Disciplina	621.381
Soggetti	Microelectromechanical systems
Lingua di pubblicazione	Inglese
Formato	Materiale a stampa
Livello bibliografico	Monografia
Note generali	Title from publisher's bibliographic system (viewed on 05 Oct 2015).
Nota di bibliografia	Includes bibliographical references and index.
Nota di contenuto	Machine generated contents note: 1. Introduction; 2. Circuit-based modeling; 3. Capacitive lumped parameter electromechanics; 4. Small-signal capacitive electromechanical systems; 5. Electromechanics of piezoelectric elements; 6. Capacitive sensing and resonant drive circuits; 7. Distributed 1D and 2D electromechanical structures; 8. Practical MEMS: pressure transducers, accelerometers and gyroscopes; 9. Electromechanics of magnetic MEMS devices; A. Review of quasistatic electromagnetics; B. Review of mechanical resonators; C. Brief survey of MEMS fabrication; D. A brief review of solid mechanics; E. Tables of M- and N-form transducer matrics; F. Finite element analysis as applied to MEMS.
Sommario/riassunto	Offering a consistent, systematic approach to capacitive, piezoelectric and magnetic MEMS, from basic electromechanical transducers to high-level models for sensors and actuators, this comprehensive textbook equips graduate and senior-level undergraduate students with all the resources necessary to design and develop practical, system-level

MEMS models. The concise yet thorough treatment of the underlying principles of electromechanical transduction provides a solid theoretical framework for this development, with each new topic related back to the core concepts. Repeated references to the shared commonalities of all MEMS encourage students to develop a systems-based design perspective. Extensive use is made of easy-to-interpret electrical and mechanical analogs, such as electrical circuits, electromechanical two-port models and the cascade paradigm. Each chapter features worked examples and numerous problems, all designed to test and extend students' understanding of the key principles.